EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	3	("20020165636"|"20020176074"|"6673637").PN.	US-PGPUB; USPAT	OR	ON	2006/03/17 09:11
L2	1343	(702/81-85).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/03/17 09:48
L3	781	(702/117,121).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/03/17 09:55
L4	591	(702/155,166,170,172).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/03/17 10:26
L5	1150	(702/182).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/03/17 10:28
L6	949	(702/183).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/03/17 10:31
L7	1036	(356/128,601,609,612).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/03/17 10:33
L8	752	(356/626,630,635).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/03/17 10:36
L9	753	(438/5,7).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/03/17 10:39
L10	2062	(438/14).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/03/17 10:43
L11	860	L10 and (optical (feed adj forward))	US-PGPUB; USPAT	OR	ON	2006/03/17 10:43
L12	933	(438/16).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/03/17 10:45
L13	661	(700/108).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/03/17 10:48
L14	642	(700/109,110).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/03/17 10:50
L15	1478	(700/121).CCLS.	US-PGPUB; USPAT	OR	OFF	2006/03/17 10:52
L16	2	optical adj metrology and feed adj forward and @pd>"20051130"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/17 11:08
L17	2	optical adj metrology and downstream and @pd>"20051130"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/17 11:09
L18	0	(wafer microelectronic semiconductor) near (fabrication manufacture manufacturing) and feed adj foward	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/17 11:09
L19	21	(wafer microelectronic semiconductor) near (fabrication manufacture manufacturing) and downstream with (parameter measurement) and @pd>"20051130"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/17 11:10
L20	0	optical adj metrology and three adj dimensional adj characterization and @pd>"20050524"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/17 11:15
L21	0	(wafer microelectronic semiconductor) near (fabrication manufacture manufacturing) and metrology same three adj dimensional adj characterization and @pd>"20050524"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/17 11:15

EAST Search History

L22	12	optical adj metrology and multiple adj wavelengths and @pd>"20051130"	US-PGPUB; USPAT; EPO; JPO; DERWENT ; IBM_TDB	OR	ON	2006/03/17 11:15
L23	11	optical adj metrology and spectrometer and @pd>"20051130"	US-PGPUB; USPAT; EPO; JPO; DERWENT ; IBM_TDB	OR	ON	2006/03/17 11:17
L24	0	(wafer and fabricationa and process and (measurement parameter) and model and optical).clm.	US-PGPUB	OR	ON	2006/03/17 11:18